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Abstract

Langmuir probes are frequently used on sounding rockets and satellites to provide measurements of plasma density, electron temperature, and spacecraft floating potential. In Earth's ionosphere, however, Langmuir probes often experience surface contamination as a result of water adsorption, dust or oil contaminants, or oxidation of the surface due to the atomic oxygen environment. In these cases, the current-voltage (IV) curve becomes distorted and produces disagreements in derived parameters dependent on the voltage sweep direction. There is general agreement within the science community that in such circumstances upsweep is more accurate. This work presents simulations for a sounding rocket in Earth's ionosphere with both a floating potential probe and a Sweeping Langmuir Probe onboard. The system's behavior is investigated as a function of the five primary parameters controlling contamination effects. We explore effects on derived plasma parameters as a function of different sweep profiles and find that the ion dwell between IV curve sweeps presents the most unaffected results despite the presence of contamination.

Langmuir Probes in Earth's Ionosphere

Langmuir probes are used to measure plasma densities and temperatures in both Earth's ionosphere as well as interplanetary space. In the case of a Sweeping Langmuir Probe (SLP), a voltage is swept across both negative and positive potentials with respect to the spacecraft chassis, and the resulting current is measured. Each currentvoltage (IV) curve, shown in Figure 1, gives a single measurement of electron and ion density, electron temperature, and can even provide insight into spacecraft charging.



Figure 1: General IV curve shown the three main collection regions. Ion saturation current is amplified for ease of viewing. Figure adapted from Barjatya [2007].

Ideally the IV curve should be independent of the sweep direction. However, in the presence of surface contamination the resulting derived plasma parameters can have disagreements between the upsweep and downsweep, and could both be wrong even if they do have agreement. Oyama et al. [2012] point to the downsweep, Piel et al. [2001] point to the upsweep, and Oyama [1976] suggests the uncontaminated solution falls somewhere in between. This work addresses the issue of surface contamination and its effect on derived plasma density and temperatures as well as charging measurements.

Surface Contamination on Langmuir Probes



Figure 2: Equivalent circuit for a probe with a contamination layer. The contamination layer is represented by R_c and C_c , Vslp is the voltage applied to the probe, and Veff is the potential seen by the plasma. The sheath and plasma can be represented by some equivalent resistance, given by Rs+Rp.

Contamination layer on the probe surface is typically modeled as a resistor and capacitor in parallel (Figure 2). The impedance between the voltage applied to the probe and the current collected is shown in the equations above. This results in not only a phase difference, but also a magnitude component in the collected current. The contamination effects can thus be separated into four regimes, as follows:

- 1. Phase and Magnitude,
- 2. Phase Only,
- 3. Magnitude Only,
- 4. Neither Phase nor Magnitude.

Example IV curves representing each regime can be found in Figure 3.



The contamination effects experienced by a Sweeping Langmuir Probe are influenced by 5 primary parameters. They are as follows:

- 1. R_C : Contamination layer resistance
- 2. $C_{\rm C}$: Contamination layer capacitance
- 3. f: Sweep Rate of the applied voltage
- 4. |I| : Magnitude of collected current
- 5. Sweep Profile

Contamination Effects on a Sweeping Langmuir Probe in Earth's Ionosphere

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$$V < V_p, \qquad I_e(V) = I_{th_e} exp(-|\frac{e(V - V_p)}{k_B T_e}|) \qquad \text{if } V > V_p, \qquad I_e(V) = I_{th_e}$$
$$I_i(V) = -I_{th_i} \left(1 - \frac{e(V - V_p)}{k_B T_i}\right)^{\beta} \qquad I_i(V) = -I_{th_i}$$
$$I_{ram}(V) = -eN_i A_{ram} v_{ram} \qquad I_{ram}(V) = -eN_i A_{ram} v_{ram}$$

Parameter		
Ion and electron temperature		
Ion and electron beta		
SLP Surface Area		
SLP ram facing area		
Ram Velocity		
Ion Mass		





Figure 7: Derived absolute percent errors as a function of SLP sweep frequency, contamination capacitance and contamination resistance for the downsweep only. The upsweep results remain unchanged.. The plasma density is fixed to 1e12 m⁻³. All other fixed parameters can be found in Table 1.

Frequency [Hz]

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Shantanab Debchoudhury

tron Dwell	lon Dwell
1.16	-0.40
-3.24	-0.76
-3.44	-0.02
5.89	1.25
150.1	-3.5
223.5	39.3

[5] Szuszczewicz E.P. and Holmes J.C., Surface contamination of active electrodes in plasmas: Distortion of conventional Langmuir probe measurements. Journal of

[6] Debchoudhury, S., Barjatya, A., Minow, J. I., Coffey, V. N., & Chandler, M. O. (2021). Observations and validation of plasma density, temperature, and O abundance from a Langmuir probe onboard the International Space Station. Journal of Geophysical Research: Space Physics, 126, e2021JA029393.